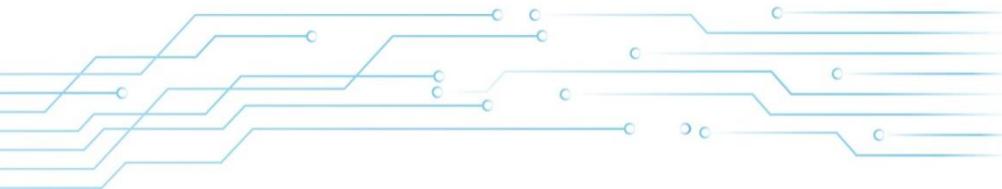


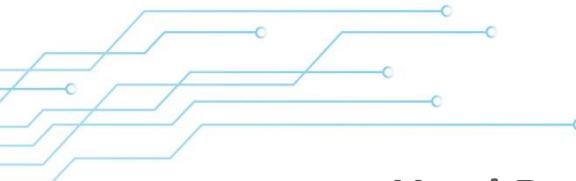


LEADING PROVIDER OF ADVANCED SEMICONDUCTOR PACKAGING  
AND TEST SERVICES FOR GLOBAL CUSTOMERS



# High Density Packaging Needs for Next Generation Connected Markets

2018.05.31



Urmi Ray

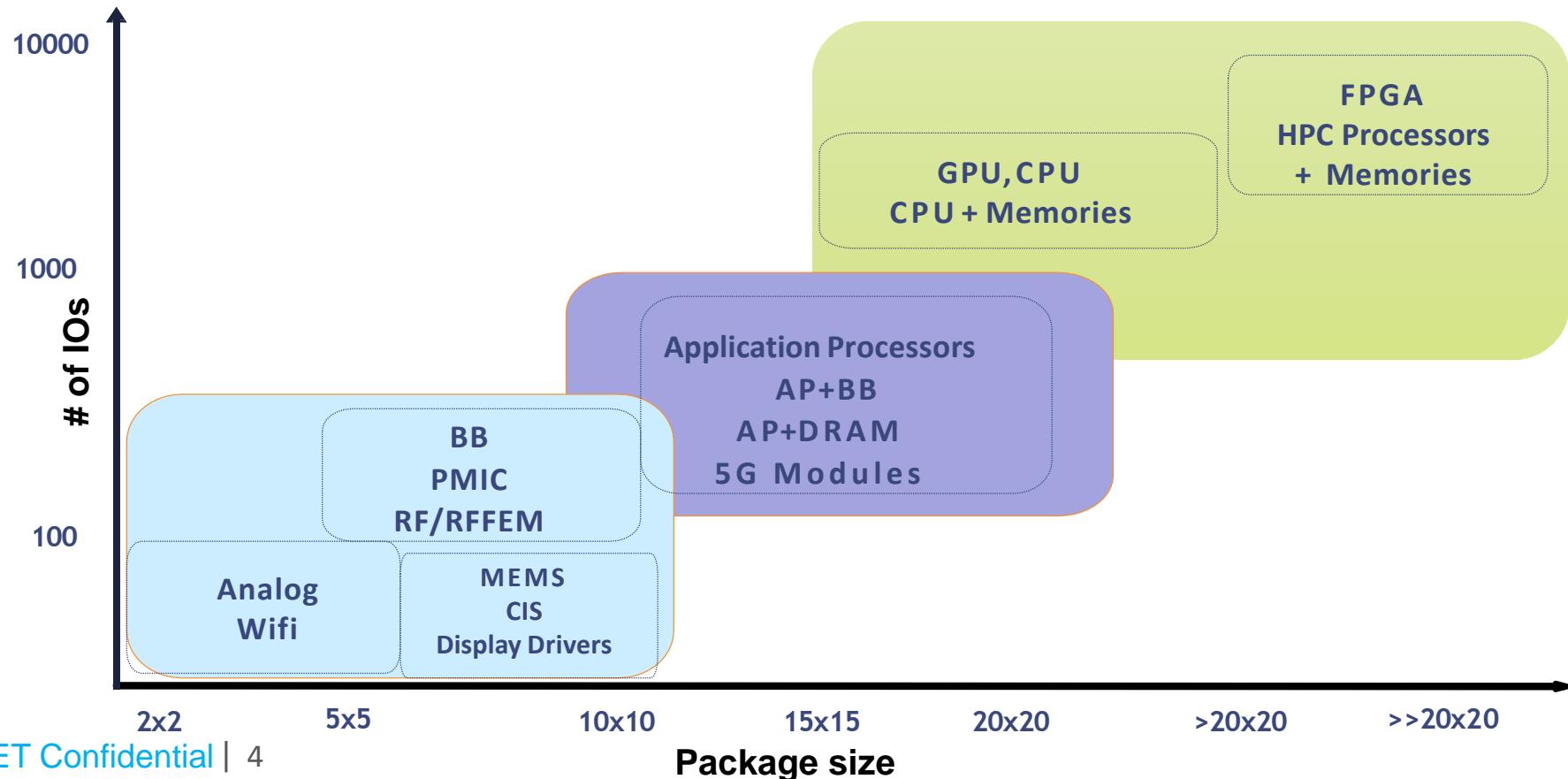


# Contents

- Industry Advanced Packaging
  - System integration and COO optimization
- eWLB as high density packaging platform
- Conclusion

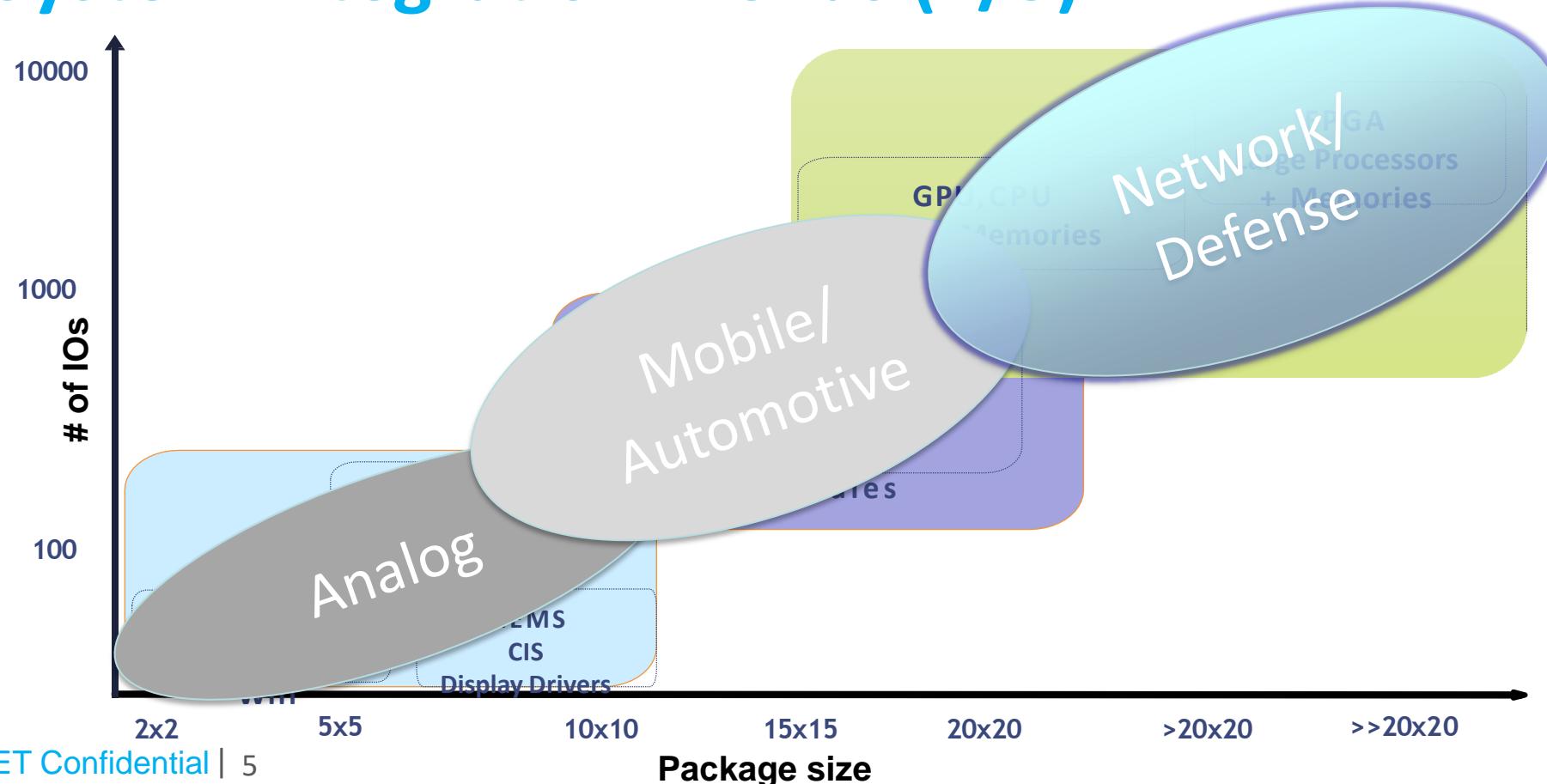


# System Integration Trends (1/5)



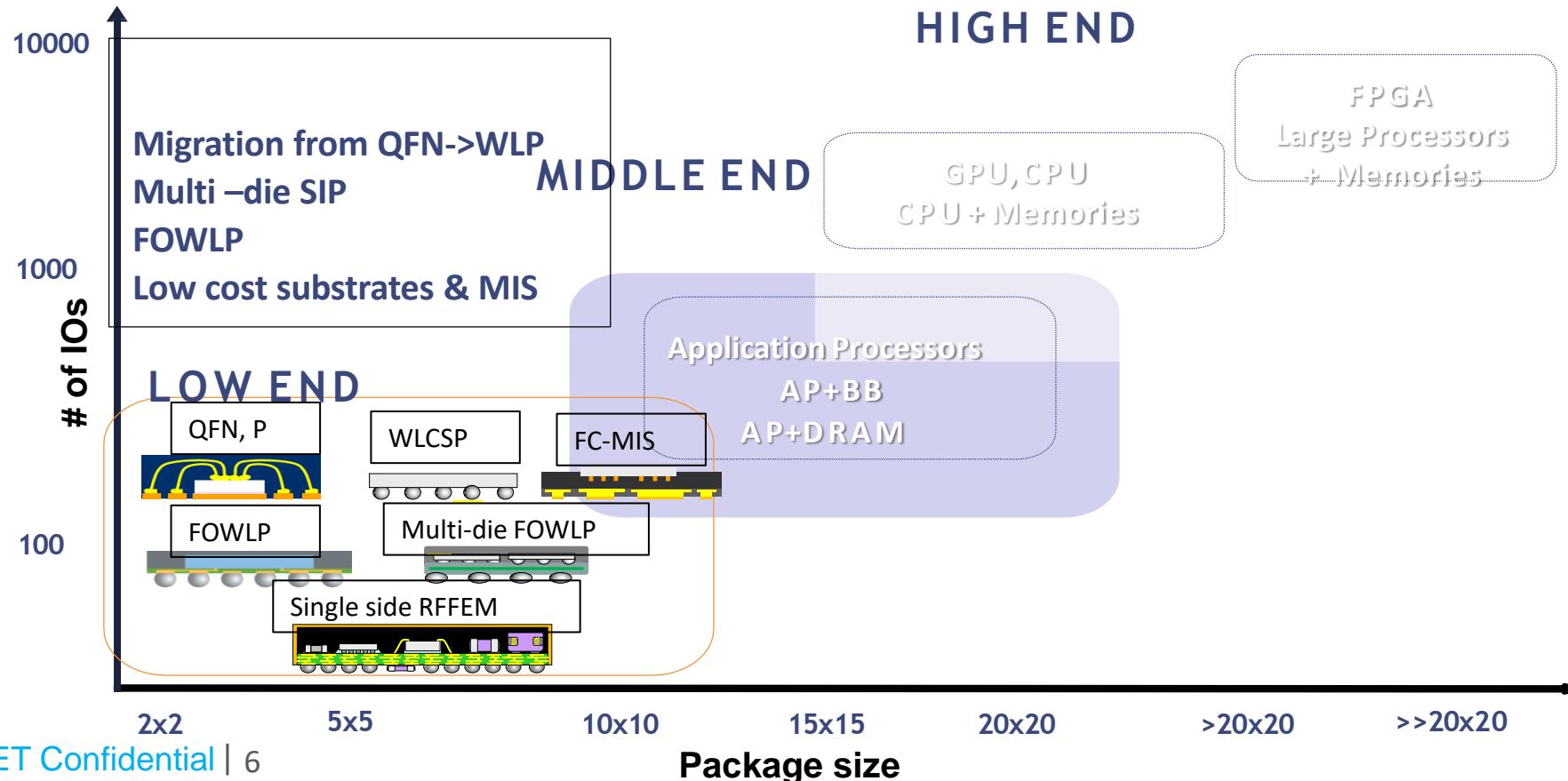


# System Integration Trends (2/5)



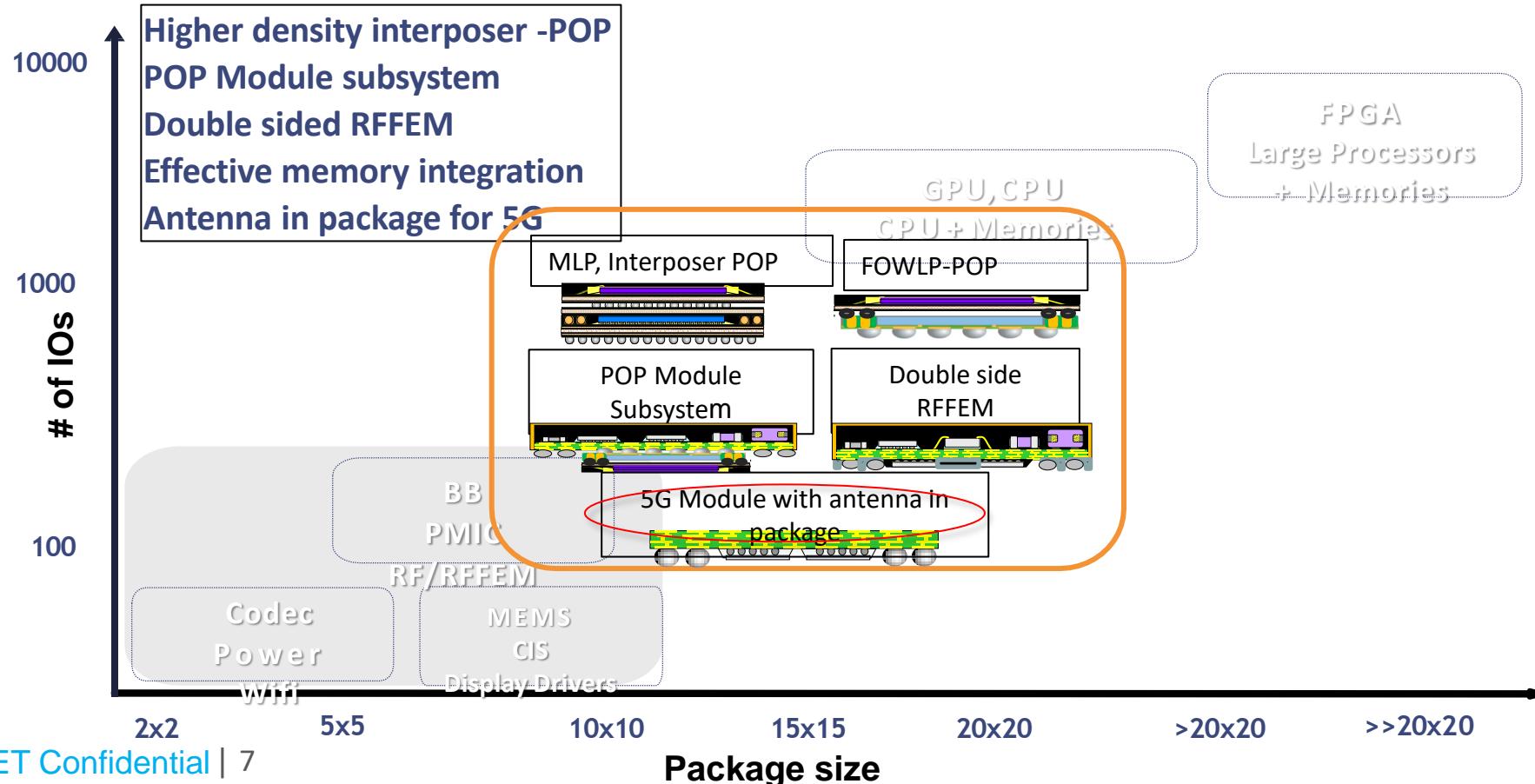


# System Integration Trends (3/5)

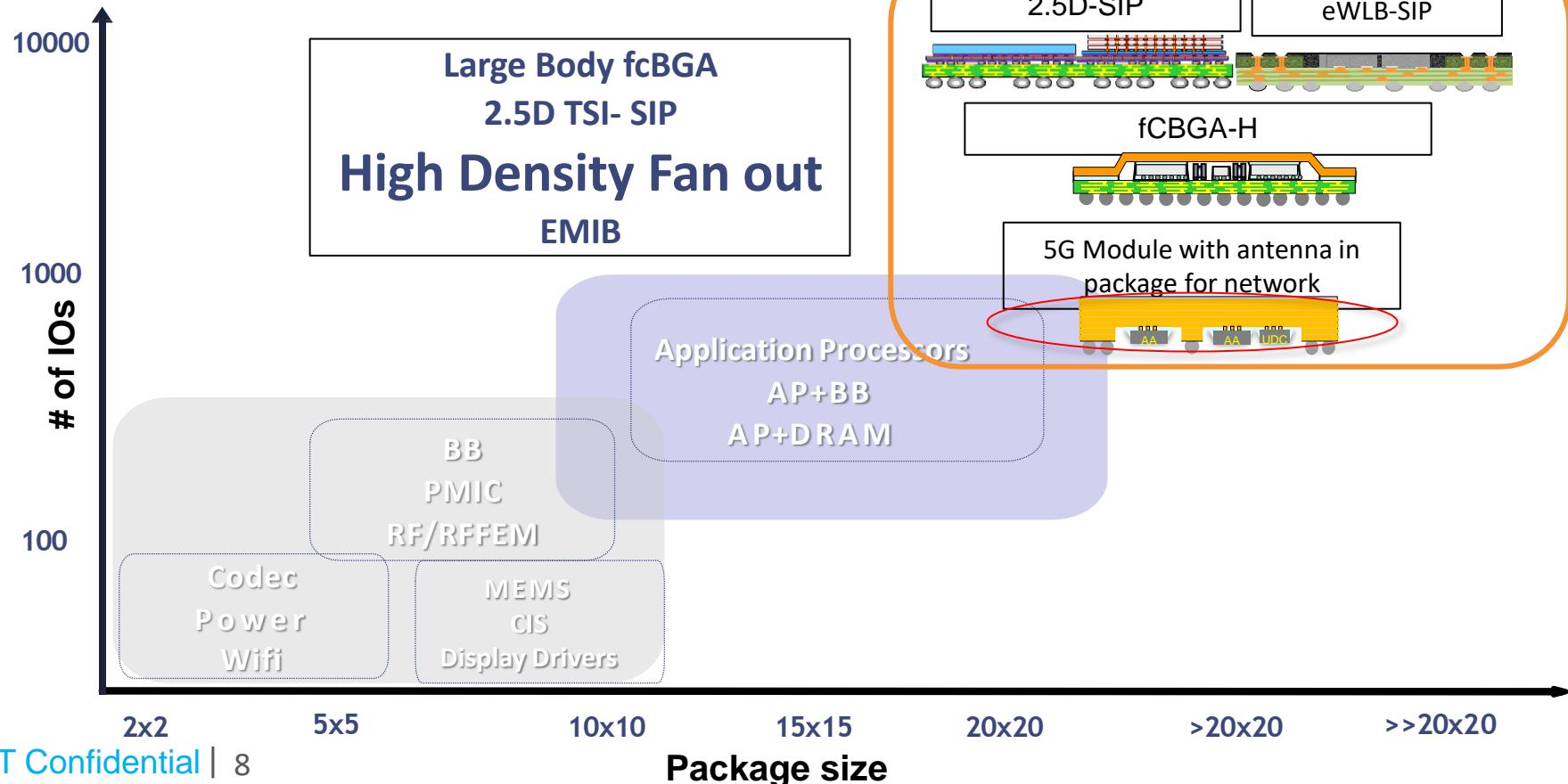


# System Integration Trends (4/5)

JCET



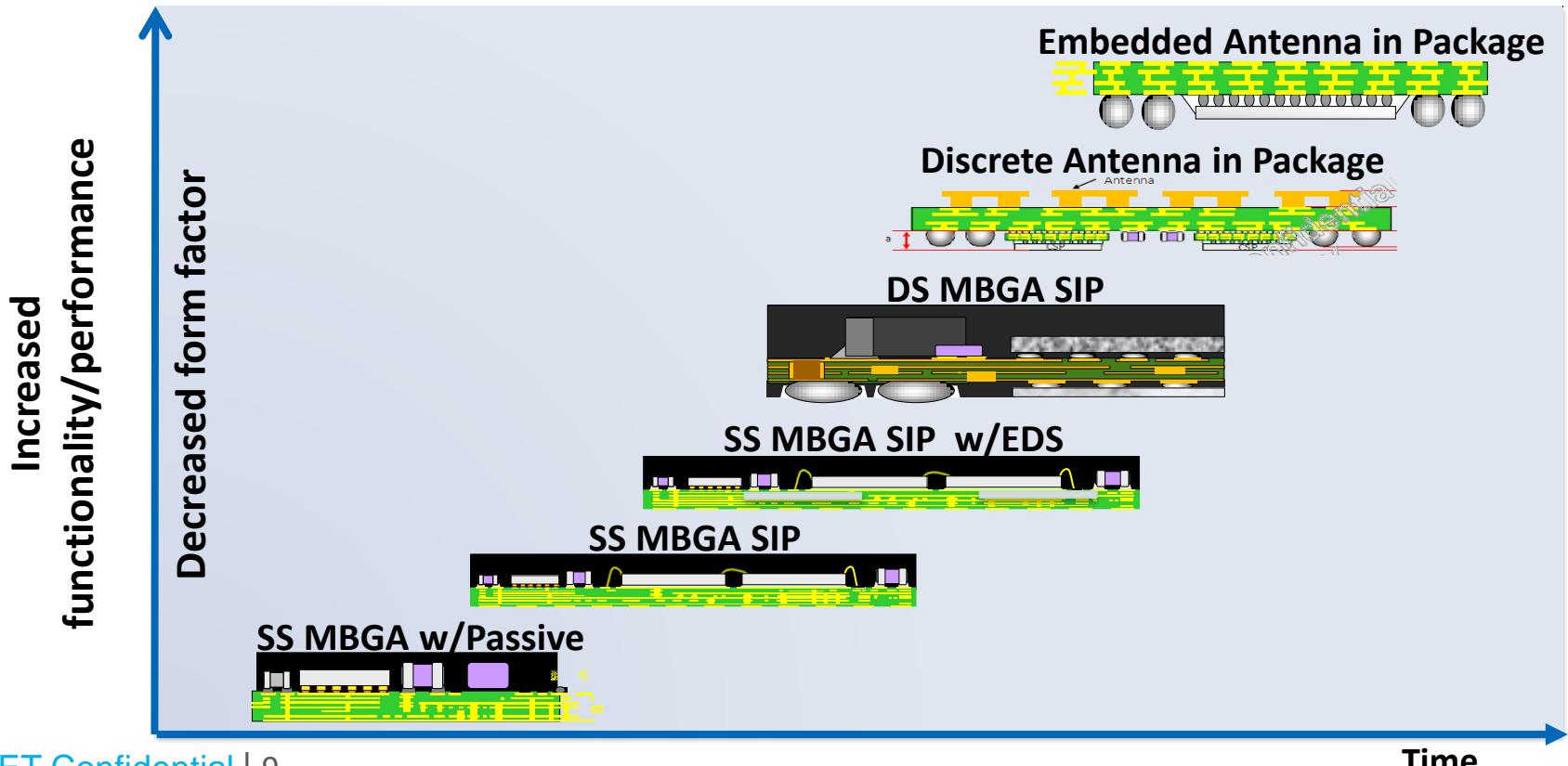
# System Integration Trends (5/5)





# Packaging Technology Towards 4G+/5G

JCET



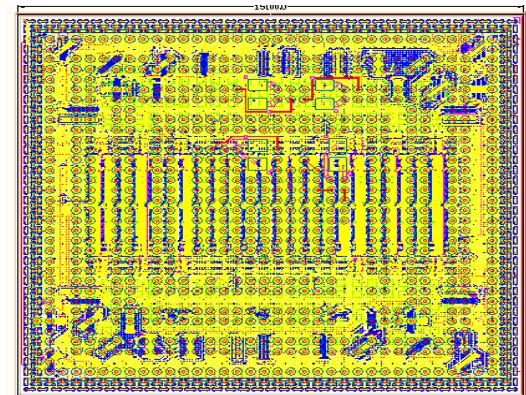
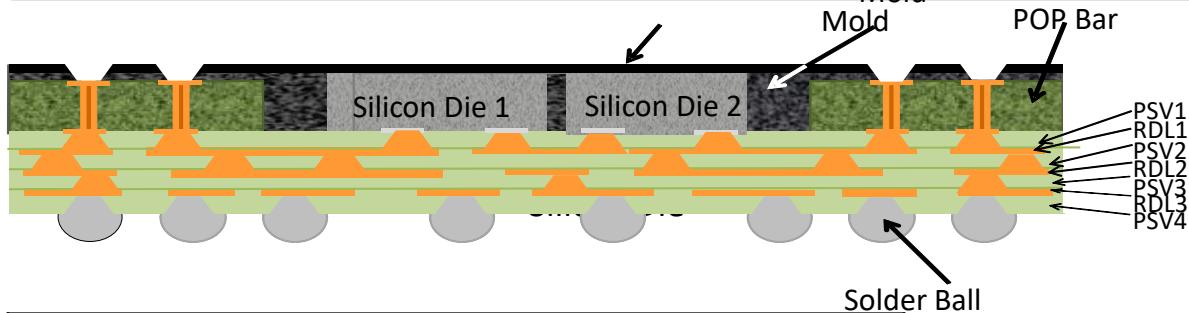
# eWLB - high density packaging platform



# High Density eWLB Package

JCET

eWLB and Fan out packages can serve as means of high density packaging  
An Example is shown here



Package Configuration (3L RDL)	
Die Size	11.16 x 5.58 mm & 11.16 x 5.58 mm
PKG Size	15x15mm
Ball Composition	SAC305
Ball Pitch (Bottom / Top)	400um / 200um
Die Thickness (min)	200um
RDL Stack Thickness (nominal)	39um
Package ball height/size	185um
PKG Total Thickness (nominal)	424um

RDL Stack	39um +/- 10um
PSV1	4um +/- 1.0um
RDL1	3um +/- 1.0um
PSV2	5um +/- 1.0um
RDL2	4um +/- 1.0um
PSV3	6um +/- 1.5um
RDL3	8um +/- 1.5um
PSV4	9um +/- 1.5um
Bump Height (SAC305)	

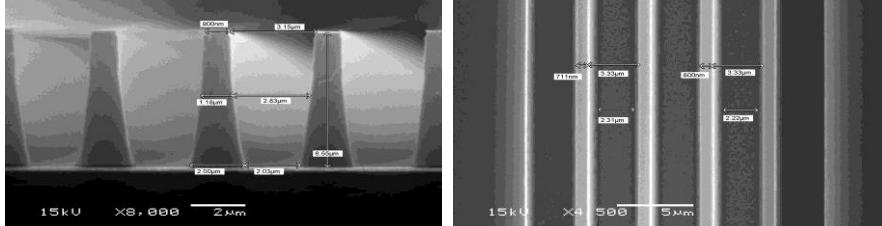
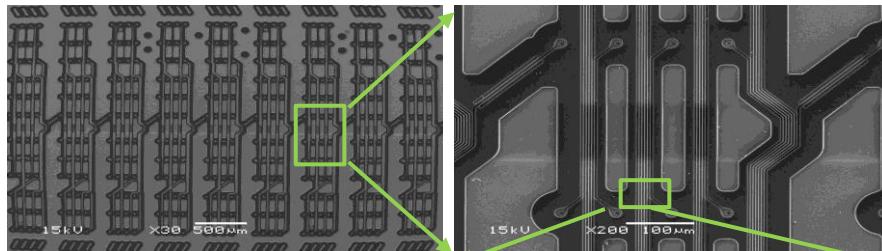
# Technology: Fine Pitch RDL1 – Litho, Plating and etching

JCET

Fine Pitch RDL Development successfully completed

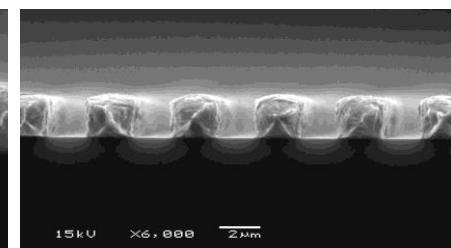
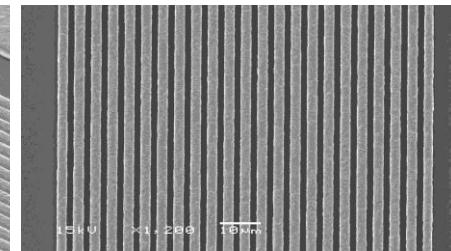
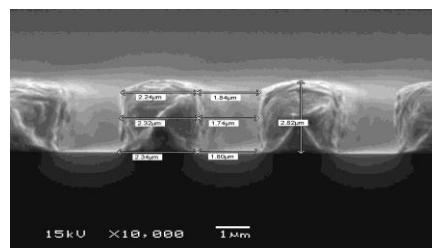
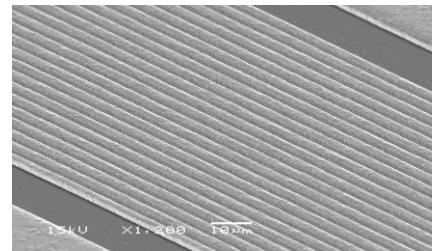
RDL1 Litho (2um L/S)

- BTM CD ~ 2.03um
- Sidewall Angle ~ 85°



RDL1 after Plating/Etch

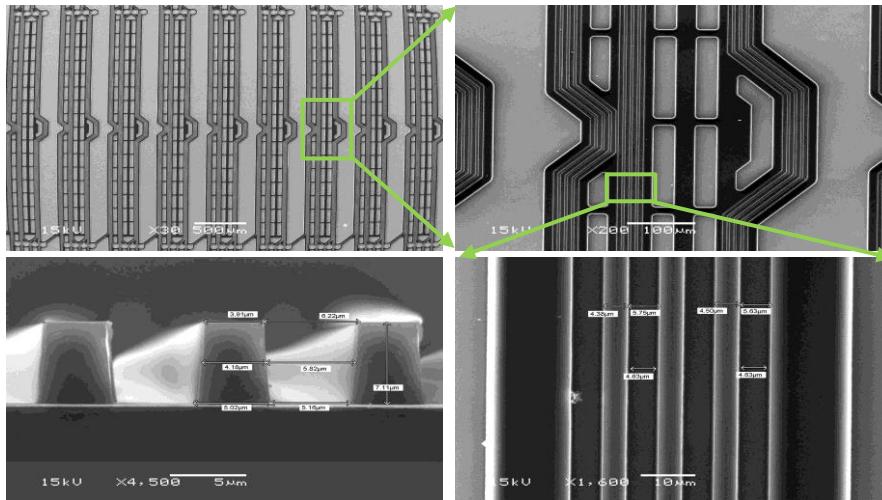
- RDL1 thickness ~ 2.82 um
- BTM CD ~ 2.34um
- Sidewall Angle ≥ 85°
- No undercut



# Technology: RDL2

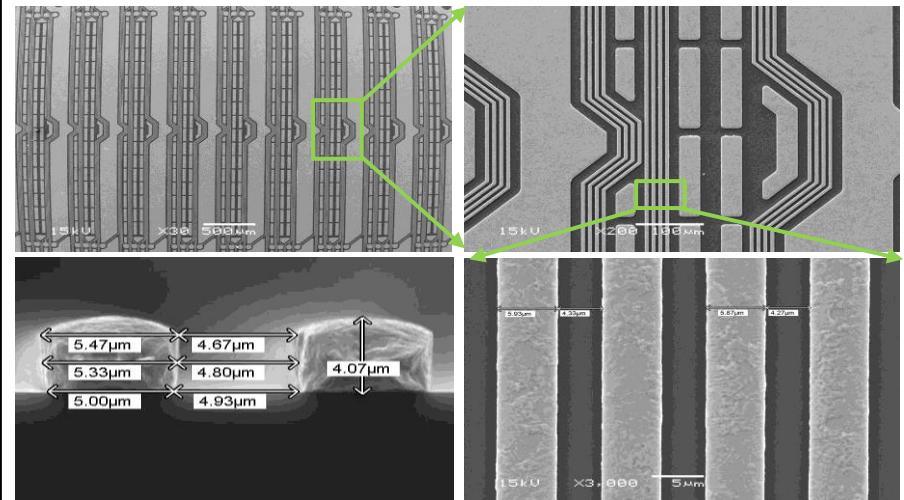
RDL2 Litho (5um L/S)

- BTM CD ~ 5.2um
- Sidewall Angle ≥ 85°



RDL2 after Plating/Etch

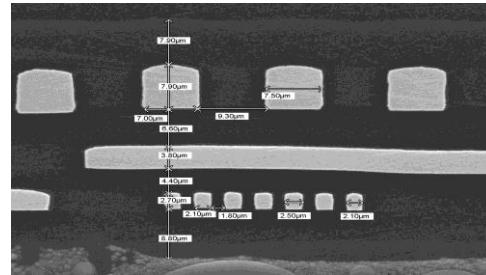
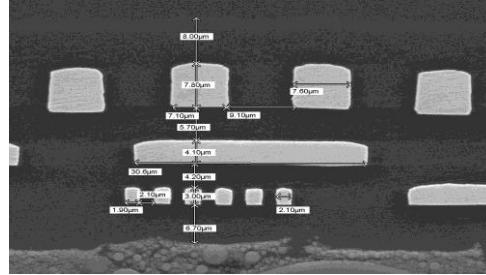
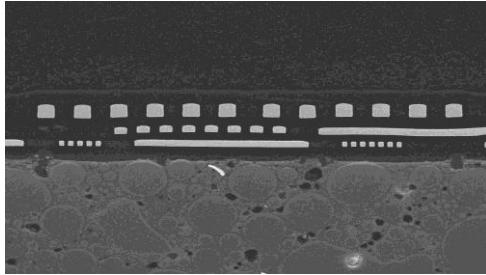
- RDL thickness ~ 4.1 um
- BTM CD ~ 5.0um
- Sidewall Angle ≥ 85°
- No undercut



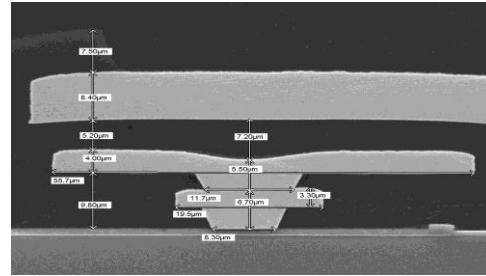
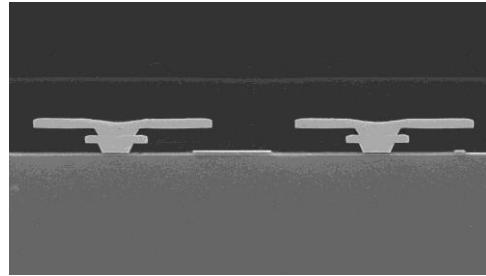
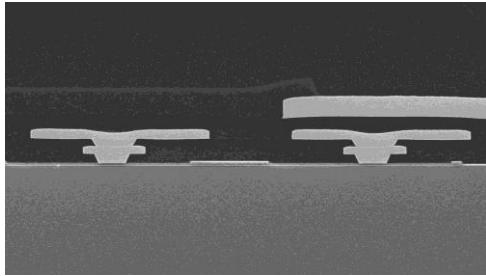
# Technology: 3L RDL – PSV Via Stack and RDL Stack

JCET

- 3L RDL Stack

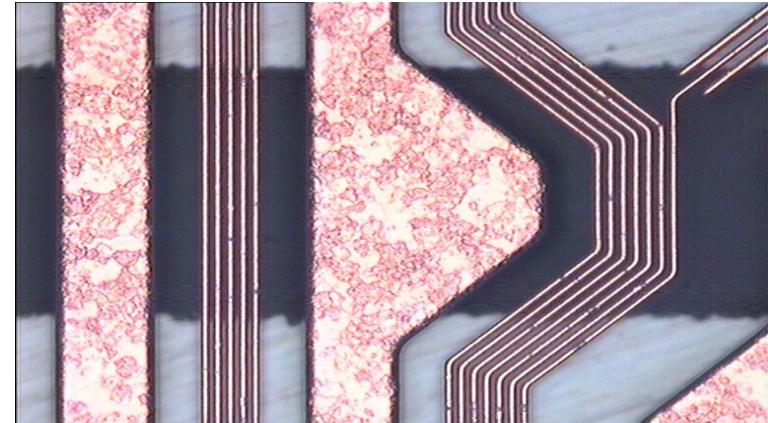
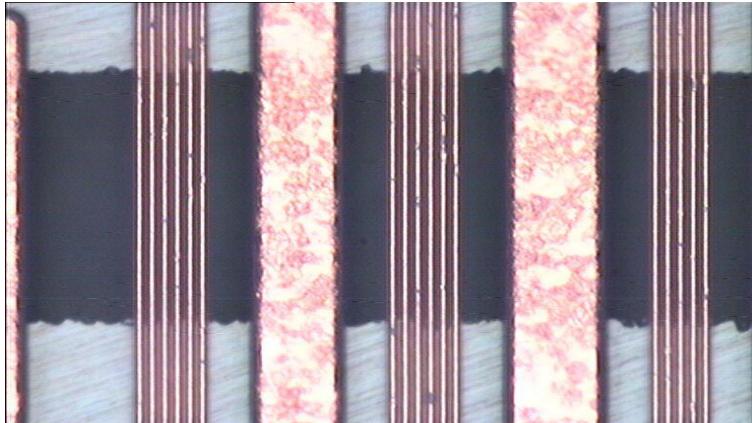
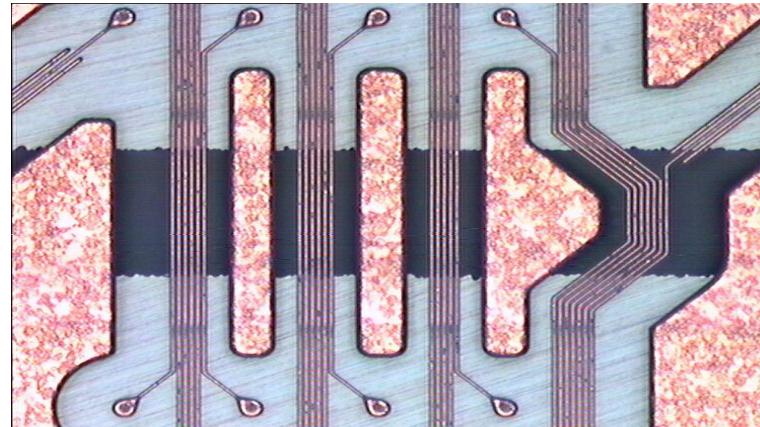


- Stacked Via

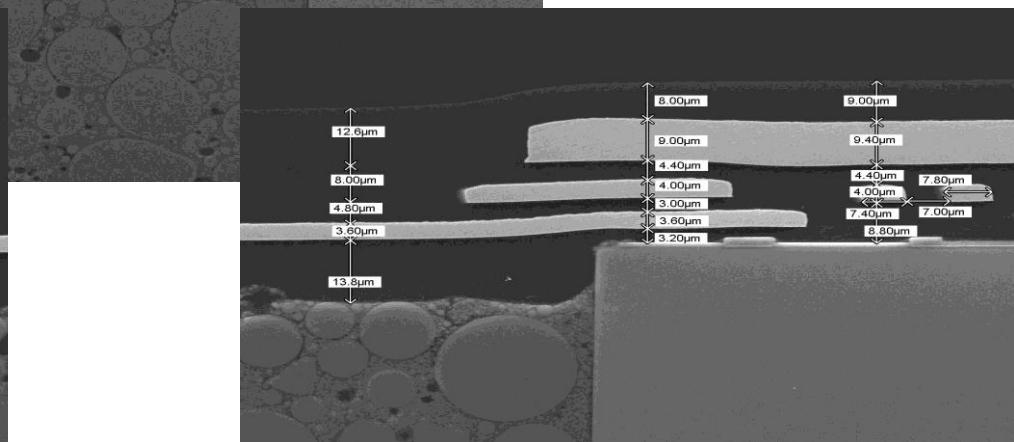
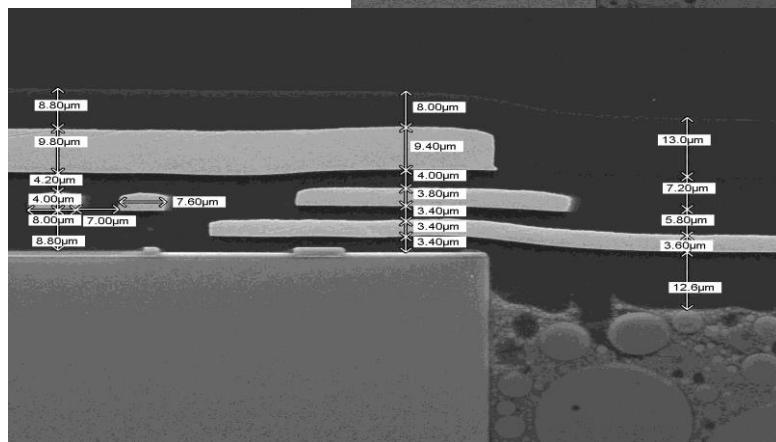


# Technology: RDL 1 (2u L/S)

JCET



# Technology: RDL1 Connection – between Die 1, Die 2 & JCET



# Conclusion





# Micro-Electronics Industry: Paradigm Changes



- Heterogeneous Integration is key enabler to solve the next decade's system challenges
- Diverse packaging solutions will provide customers with cost-effective solutions
- Successful product introductions will be facilitated by partnership and collaboration across supply chain partners:
  - OEMs/system houses
  - Design houses
  - Foundries/OSATs
  - Materials suppliers
  - Component vendors



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